Claim Amendments:

This listing of claims will replace all prior versions, and listings, of claims in the application:

- 1. (Currently Amended) A single crystal spinel boule formed by melt processing, the boule having a non-stoichiometric composition and having a reduced mechanical stress or strain represented by a yield rate not less than about 20%, wherein yield rate is w_i/(w_i + w_i) × 100%, w_i = the number of intact wafers processed from said boule, and w_i = the number of fractured wafers from said boule due to internal mechanical stress or strain in the boule represented by the general formula aAD·bE₂D₃, wherein A is selected from the group consisting of Mg. Ca. Zn. Mn. Ba. Sr. Cd. Fe. and combinations thereof. E is selected from the group consisting Al. In. Cr. Sc. Lu. Fe, and combinations thereof, and D is selected from the group consisting O. S. Se. and combinations thereof, wherein a ratio b:a > 2.5:1 such that the spinel is rich in E₂D₃.
- 2. (Currently Amended) The boule of claim 1, having a reduced mechanical stress or strain represented by a yield rate not less than about 20%, wherein yield rate is $w_i/(w_i + w_f) \times 100\%$, $w_i =$ the number of intact wafers processed from said boule, and $w_f =$ the number of fractured wafers from said boule due to internal mechanical stress or strain in the boulewherein the yield rate is not less than about 25%.
- 3. (Currently Amended) The boule of claim 12, wherein the yield rate is not less than about 30%.
- 4. (Currently Amended) The boule of claim 13, wherein the yield rate is not less than about 40%.
- 5. (Currently Amended) A single crystal spinel wafer formed by melt processing, the wafer having a non-stoichiometric composition and having a reduced internal stress or strain represented by a yield rate not less than about 20%, wherein yield rate is $w_i/(w_i + w_i) \times 100\%$, w_i = the number of intact wafers processed from the boule, and w_i = the number of fractured wafers

from the boule due to mechanical stress or strain in the boule represented by the general formula aAD·bE₂D₃, wherein A is selected from the group consisting of Mg, Ca, Zn, Mn, Ba, Sr, Cd, Fe, and combinations thereof, E is selected from the group consisting Al, In, Cr, Sc, Lu, Fe, and combinations thereof, and D is selected from the group consisting O, S, Se, and combinations thereof, wherein a ratio b:a > 2.5:1 such that the spinel is rich in E₂D₃.

- 6. (Original) The single crystal spinel wafer of claim 5, wherein the wafer has a diameter of not less than about 1.75 inches.
- 7. (Original) The single crystal spinel wafer of claim 5, wherein the wafer has a diameter of not less than about 2.0 inches.
- 8. (Original) The single crystal spinel wafer of claim 5, wherein the wafer has a diameter of not less than about 2.5 inches.
- 9. (Original) The single crystal spinel wafer of claim 5, wherein the boule consists essentially of a single spinel phase, with substantially no secondary phases.
 - 10. (Canceled)
- 11. (Currently Amended) The single crystal spinel wafer of claim 105, wherein A is Mg, D is O, and E is Al, such that the single crystal spinel has the formula aMgO•bAl₂O₃.
- 12. (Currently Amended) The single crystal spinel wafer of claim 105, wherein the ratio b:a is not less than about 1.2:13:1.
- 13. (Currently Amended) The single crystal spinel wafer of claim 105, wherein the ratio b:a is not less than about 2.91.5:1.
- 14. (Currently Amended) The single crystal spinel wafer of claim 105, wherein the ratio b:a is not less than about 2.0:1 wherein the wafer has a reduced internal stress or strain represented by a yield rate not less than about 20%, wherein yield rate is w_i/(w_i + w_f) x 100%, w_i

= the number of intact wafers processed from a boule, and w_f = the number of fractured wafers from the boule due to mechanical stress or strain in the boule.

- 15. (Canceled).
- 16. (Currently Amended) The single crystal spinel wafer of claim 105, wherein the ratio b:a is not greater than about 4:1.
- 17. (Currently Amended) The single crystal spinel wafer of claim 105, wherein the wafer has a lower mechanical stress and strain compared to stoichiometric spinel.
- 18. (Currently Amended) An optoelectronic substrate, consisting essentially of aMgO•bAl₂O₃ single crystal spinel, wherein a ratio b:a > 2.54:1 such that the spinel is rich in Al₂O₃, and the single crystal spinel is formed by a melt process.
 - 19. (Original) The substrate of claim 18, wherein the substrate comprises a wafer.
- 20. (Original) The substrate of claim 18, wherein the substrate comprises a die formed from a wafer.
 - 21. (Original) The substrate of claim 20, wherein the die is cleaved from the wafer.
- 22. (Original) The substrate of claim 18, wherein the substrate has a surface suitable for epitaxial growth of an active layer thereon.
 - 23-29. (Canceled).